

# Silicon Sensor Study for ILD ECAL

CALICE Collaboration Meeting @ LAPP  
Sep. 9<sup>th</sup> – 11<sup>th</sup>, 2013

Tamaki Yoshioka  
Kyushu University



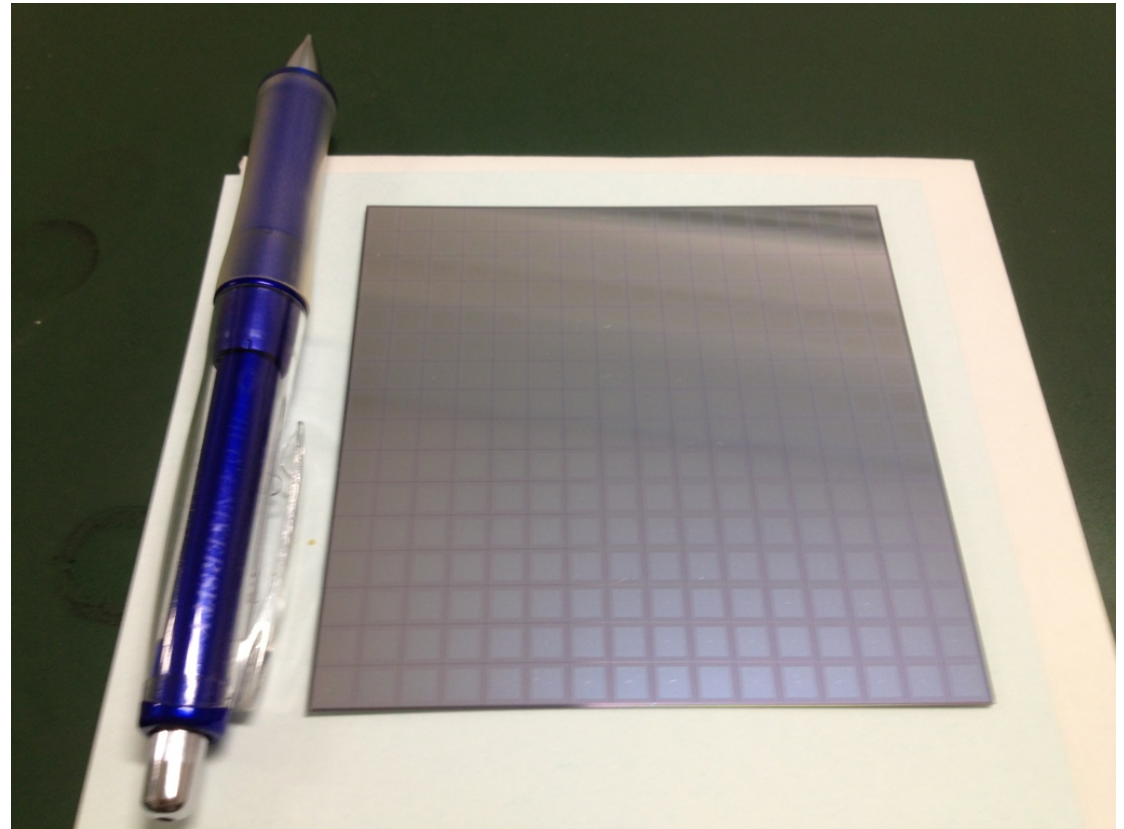
# *Contents*

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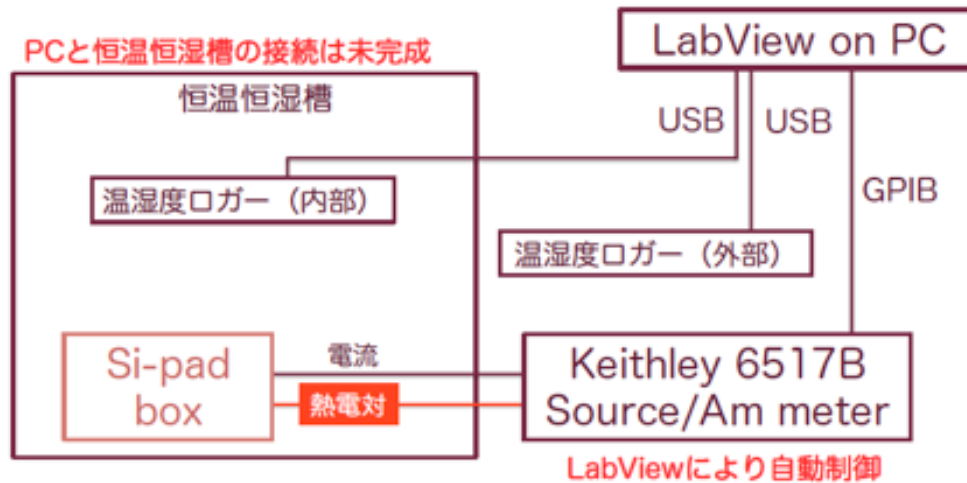
- Measurement of basic properties
  - I-V measurement
  - C-V measurement
- Activities at Kyushu University
- Activities at University of Tokyo
- Summary

# *Silicon Sensor for ECAL*

- Produced by Hamamatus Photonics K.K.
- $16 \times 16 = 256$  pixels in total
- Pixel size :  $5 \times 5 \text{ mm}^2$
- Thickness :  $300\mu\text{m}$

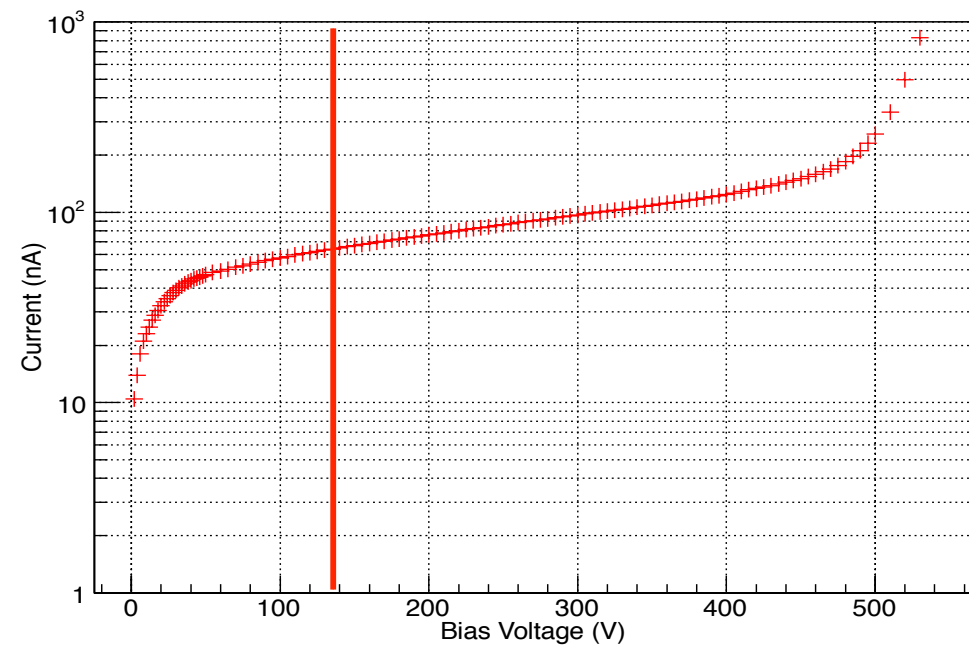


# I-V Measurement

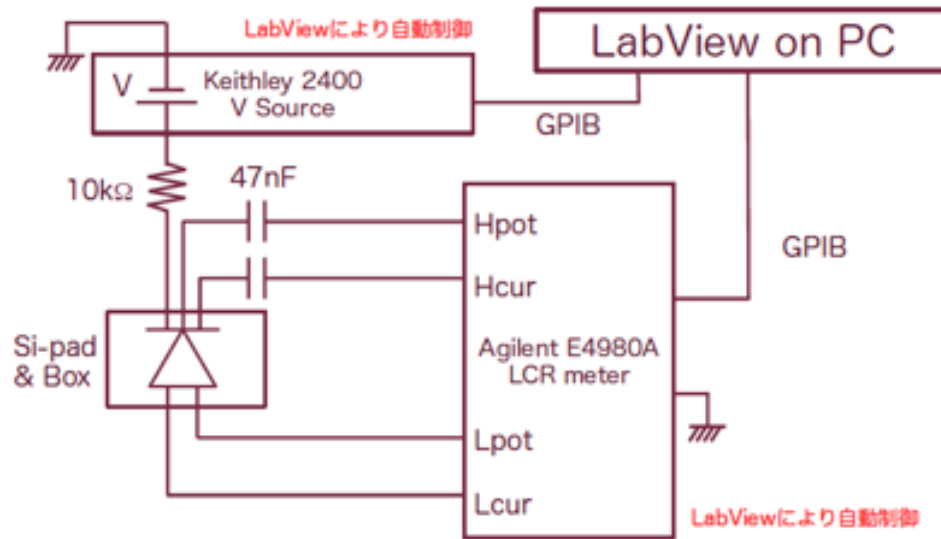


- Temperature/Humidity is controlled.
- Data taking is controlled by Labview (PC).

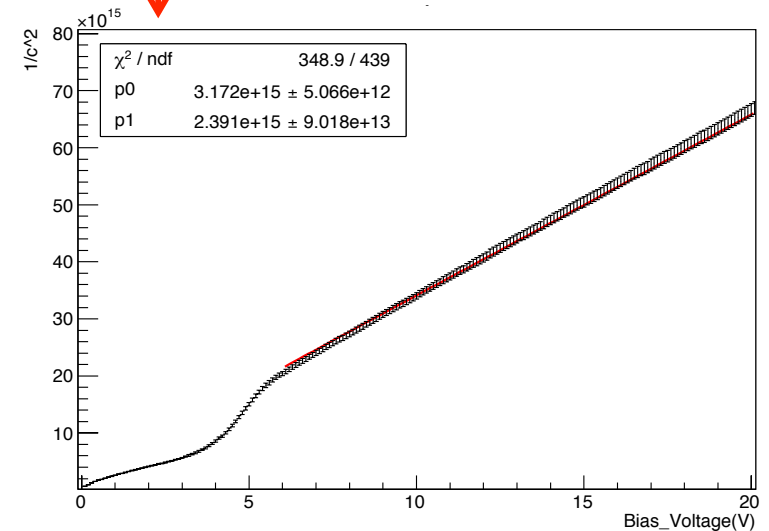
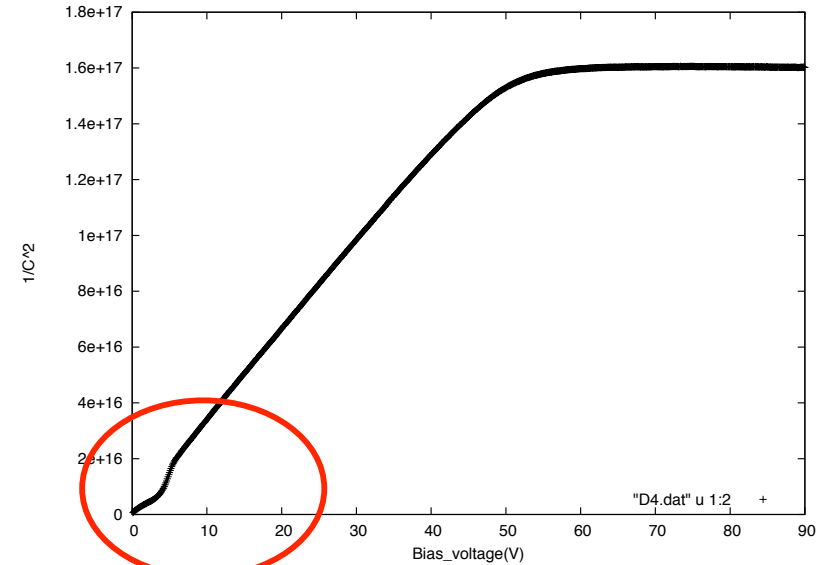
- Leakage current at the operation voltage (120V) is  $< 100$  nA



# C-V Measurement

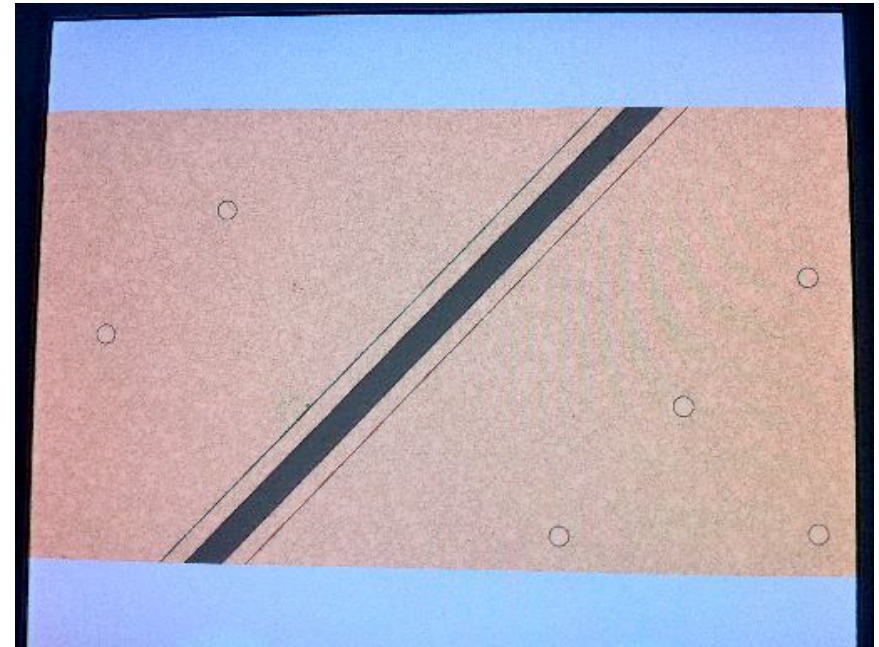


- 6 – 45 V : linear
- > 45 V : saturated (full depletion)
- < 6V : due to the MOS structure



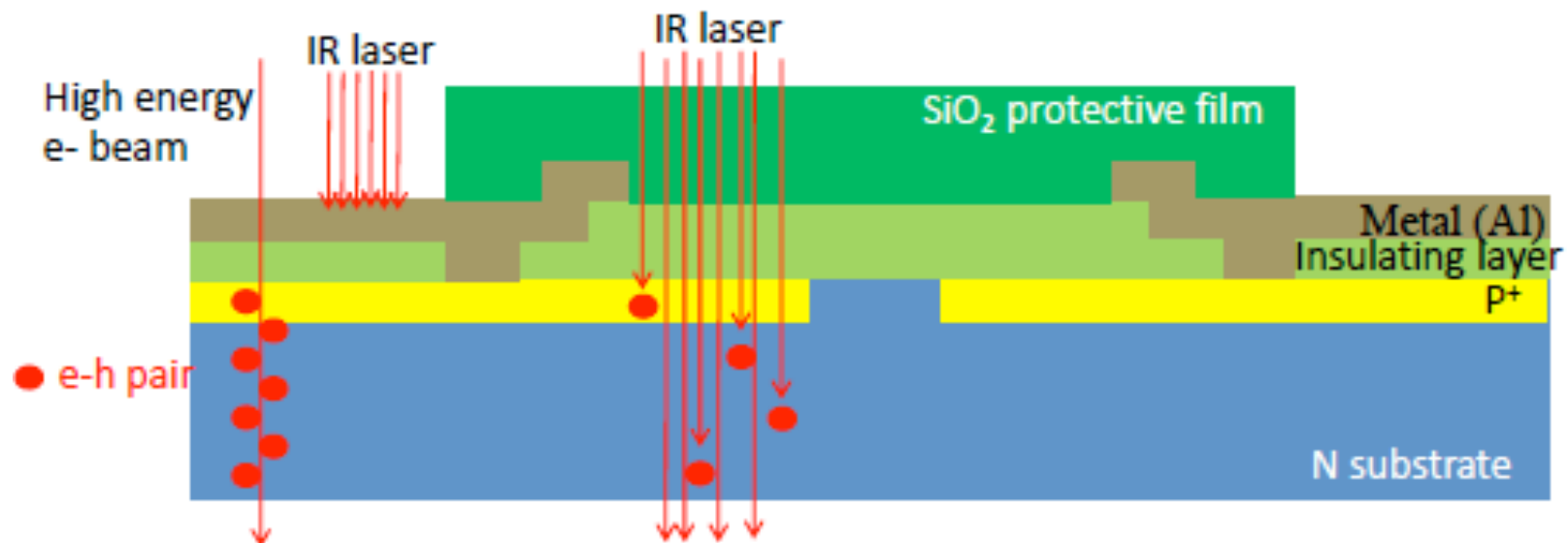
# *Activities at Kyushu Univ.*

- We are going to study the cross talk and signal behavior systematically.
- We are setting up the infrared laser system for this purpose.



# Infrared Laser

- Wave length  $\rightarrow$  1064 nm = 1.16 eV
- Energy gap of Si = 1.12 eV
- Average production energy of e-h pair = 3.6 eV
- Almost all laser light go through a Si sensor, but they can make e-h pair a certain probability.  
 $\rightarrow$  We can make e-h pair uniformly in a sensitive area.



# Infrared Laser System

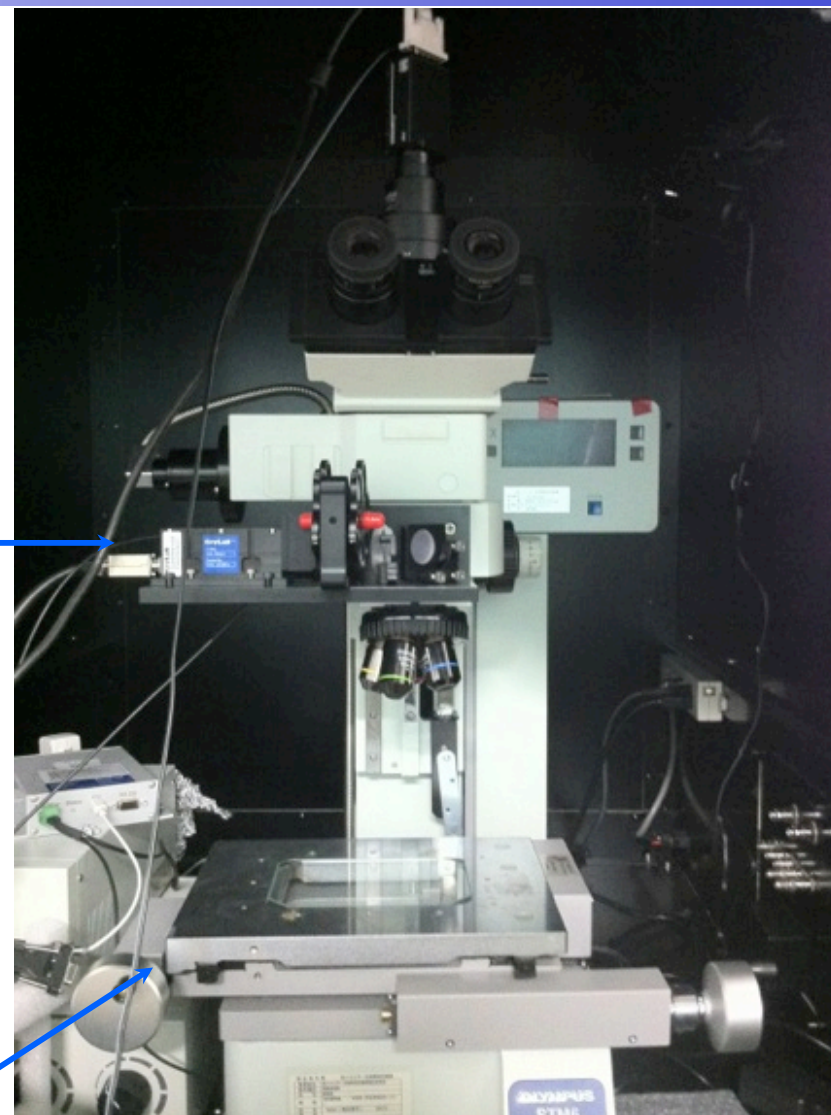
CRYLAS GmbH  
DSS1064-Q2 (Class 3B)  
Wave length : 1064 nm  
Pulse width : ~ 1.5 ns  
Pulse energy : > 20  $\mu\text{J}/\text{pulse}$   
                  ~  $10^{14}$  photons/pulse  
Peak power : > 13kW  
Reputation rate : 1 ~ 10kHz

Interface of the control software



2013/Sep/11

Laser  
Trigger  
ND-filters  
mirror



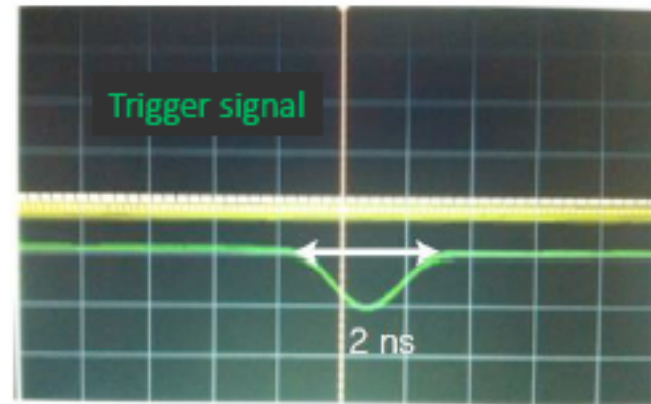
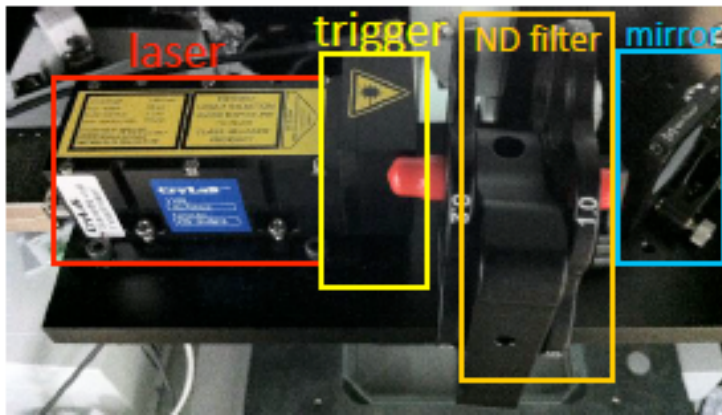
x-y stage

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# *Infrared Laser System*

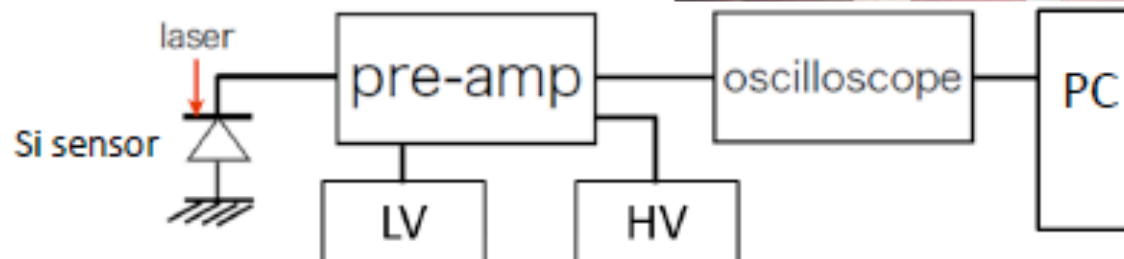
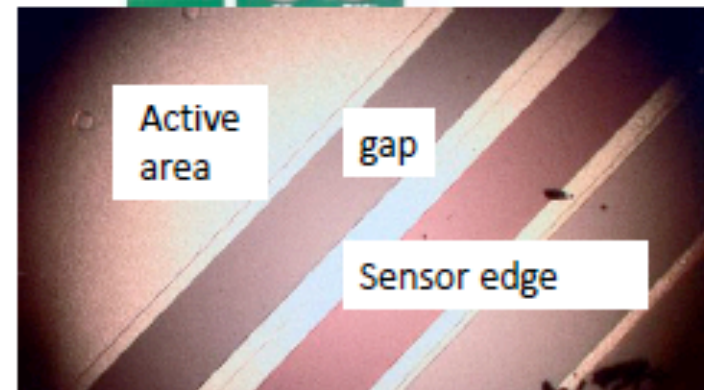
- Trigger module attached just after laser module.
- We can reduced and control laser power with ND-filters.



- Trigger signal is made in front of laser injection.

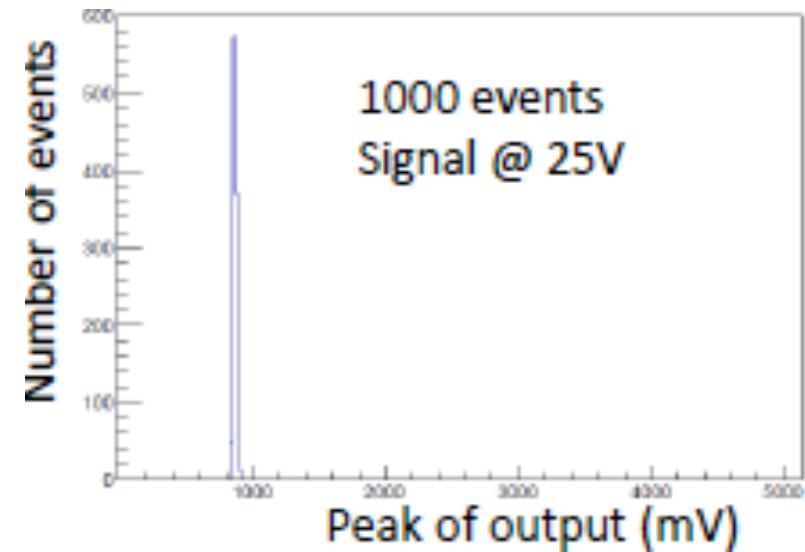
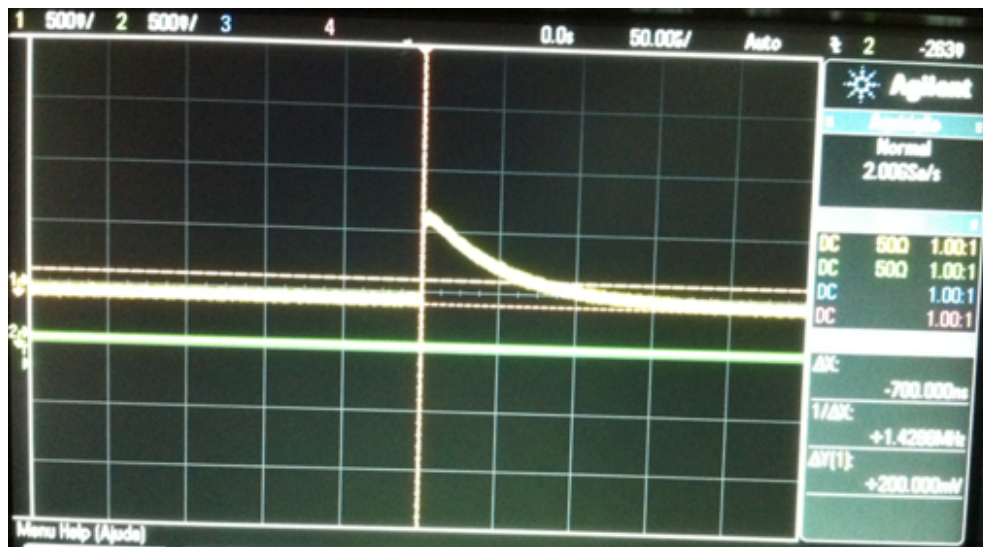
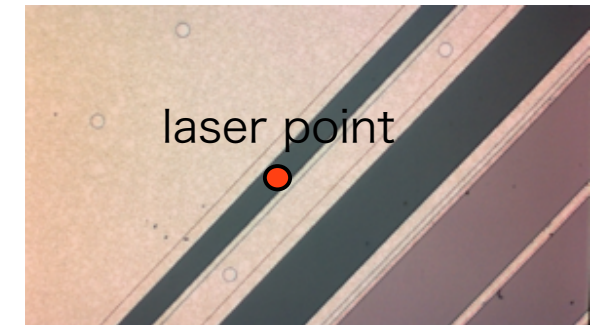
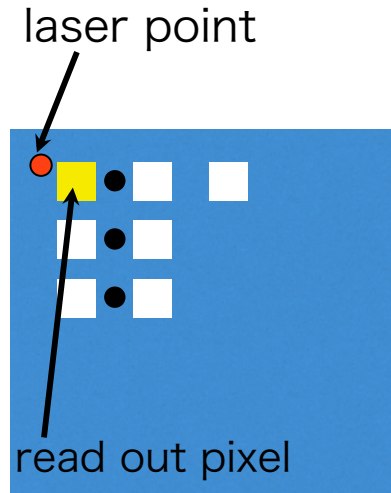
# Setup

- Laser light is focused on gap between cell edge and sensor gap
- Laser diameter :  $< 23\mu\text{m}$  (gap is  $32\mu\text{m}$ )
- Only one channel can be read out for now (one of the corner edge)



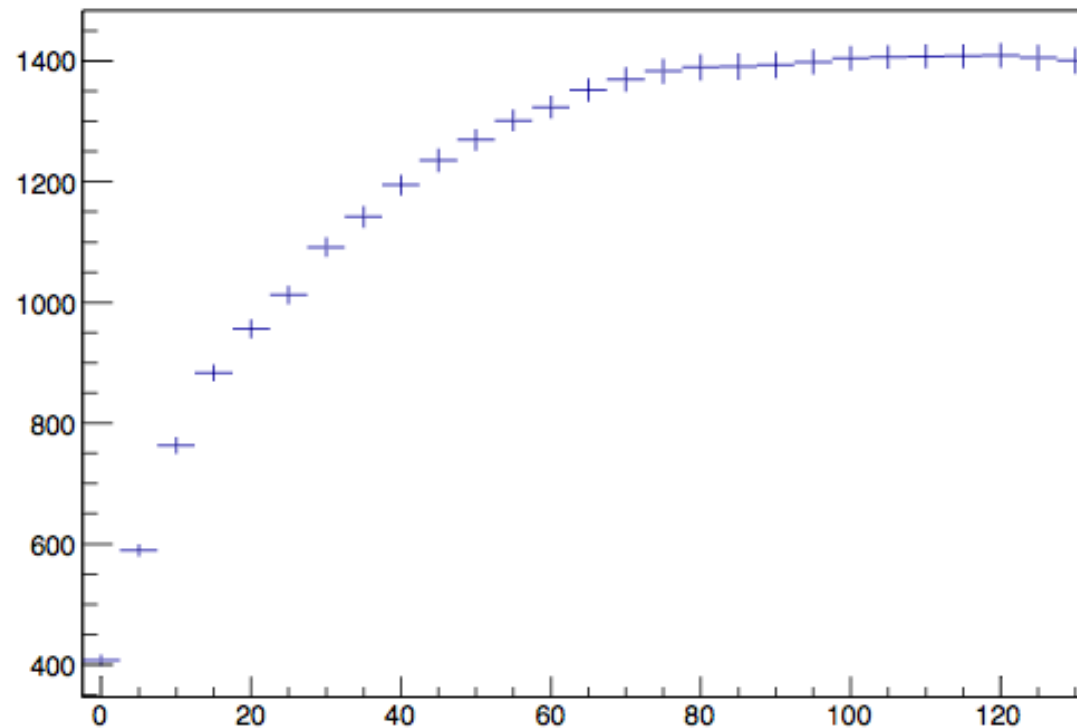
# Setup (Cont'd)

- We measured the laser signal with oscilloscope
- Get peak value from each event
- Fit with gaussian function  
→ fluctuation of peak value  $\sim 1\%$



# Result

- Bias Voltage scan ranging from 0 to 130 V
- the saturation occurs because of full depletion



# *Activities at Univ. of Tokyo*

Daniel Jeans, Yoshio Kamiya, Sachio Komamiya  
Chihiro Kozakai, Shion Chen

Aim:

- Develop silicon sensor testing station for quality control

Along the way:

- measure and understand sensor properties
  - > define suitable QC tests
- measure effects of radiation damage
  - > confirm expected absence of adverse effects @ ILC doses

# *Activities at Univ. of Tokyo*

We have developed computer-controlled system to measure  
I-V and C-V characteristics of sensors

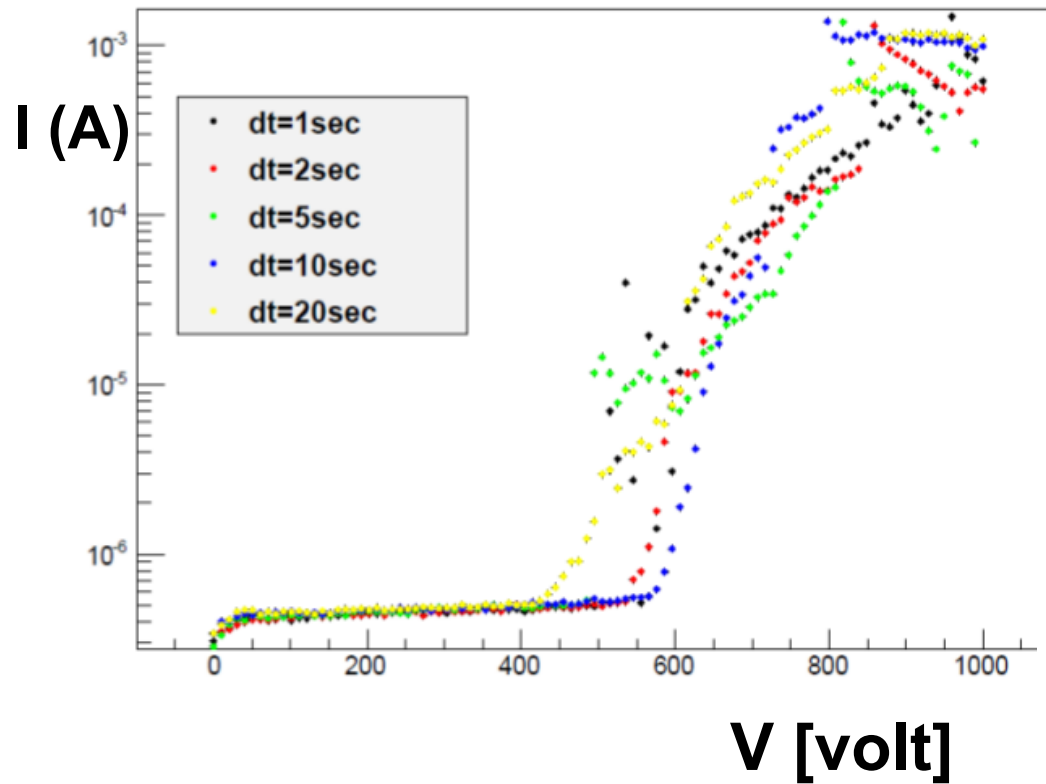
based on Keithley pico-ammeter, Agilent LCR meter, custom GUI

We have started using the system to measure properties of a few sensors

e.g. V-I curves, determination of breakdown voltage  
Transient effects after HV turn-on  
Temperature dependence  
Capacitance vs. Voltage  
contribution of si bulk and of MOS structure at pixel

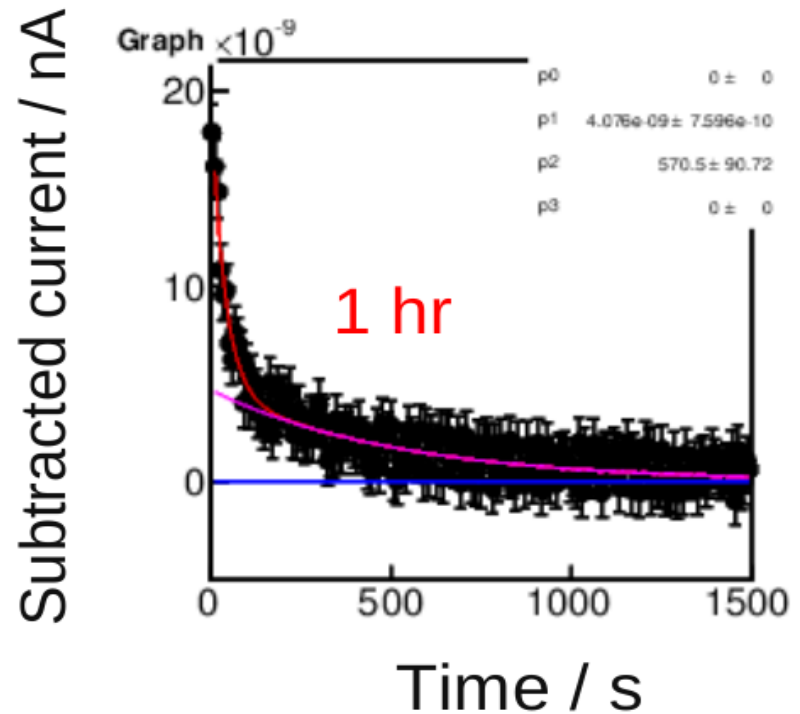
Compare measurements to expectations  
to gain confidence in measurement procedure

V-I characteristics seem to depend on time between measurements in unusual way...

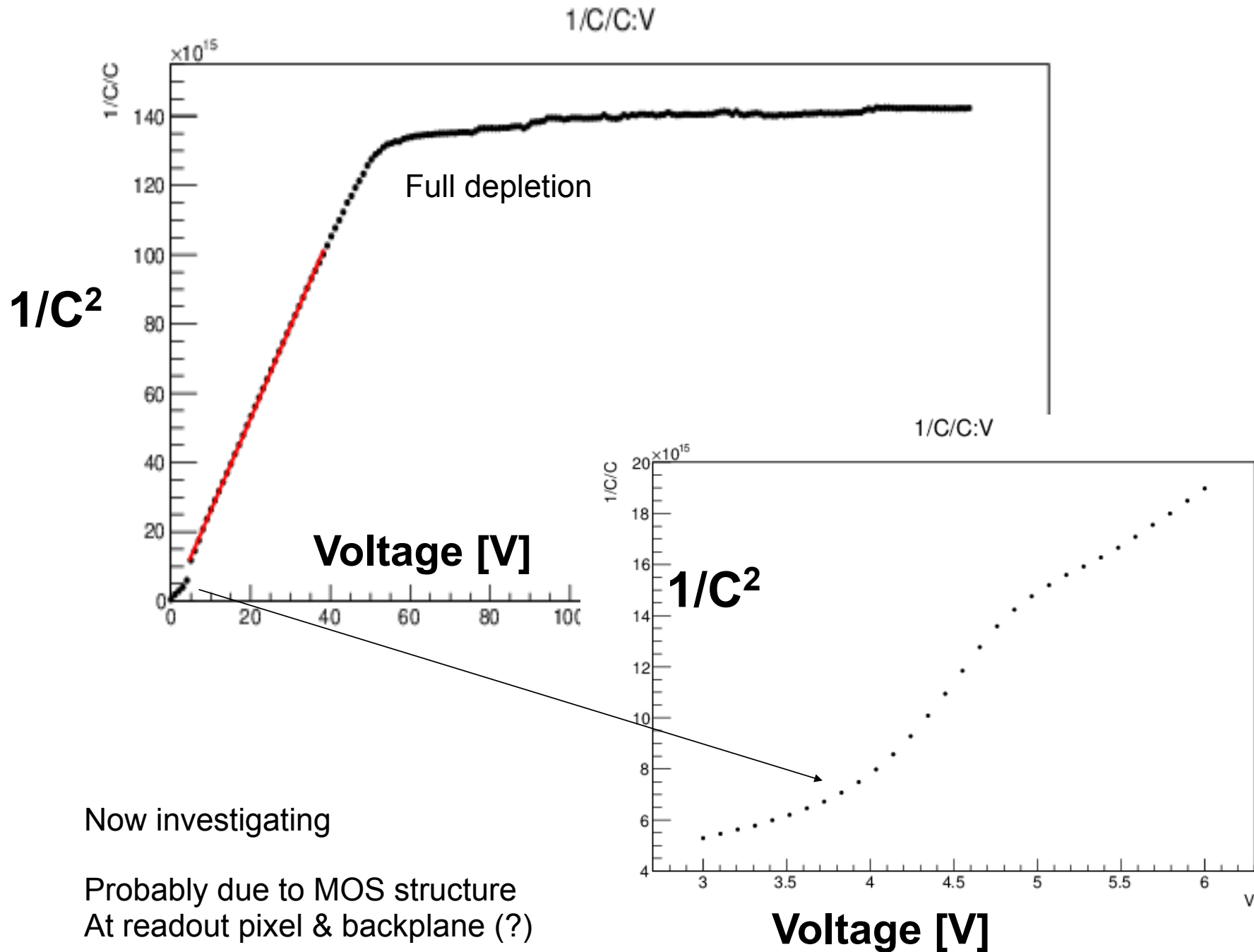


Some examples of first measurements

Transient currents after turn-on of HV



# Example of C-V measurements





# *Summary*

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- Both Kyushu/Tokyo group developed computer-controlled silicon sensor test bench in order to measure its properties (I-V, C-V etc).
- We will continue the measurements of several sensors with different designs.
- Kyushu group will continue the study with IR laser system.
- Tokyo group will study the radiation damage of the sensor with neutrons.

# International Workshop on Future Linear Colliders

# LCWS13

11-15 November 2013, The University of Tokyo

The workshop will be devoted to the study of the physics case for a high energy linear electron-positron collider, taking into account the recent results from LHC, and to review the progress in the detector and accelerator designs for both ILC and CLIC projects.

Website: <http://www.icepp.s.u-tokyo.ac.jp/lcws13/>

Contact: [lcws13@icepp.s.u-tokyo.ac.jp](mailto:lcws13@icepp.s.u-tokyo.ac.jp)

LCWS13 will be held at The University of Tokyo

11-15 November 2013 (registration is ongoing)

<http://www.icepp.s.u-tokyo.ac.jp/lcws13/>

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